

國立成功大學統計學系

專題演講

時 間：109 年 4 月 23 日 (星期四) 下午 3:30 – 5:00

地 點：統計學系三樓視聽教室 (62331)

演講者：鄭順林 教授

國立成功大學 統計系

題 目：Clustering wafer bin maps when some of them are partially masked

Abstract

We construct a new procedure for clustering partially masked images from wafer bin maps (WBMs). A WBM is an image of bin codes from circuit probe tests on a wafer after a semiconductor manufacturing process. Certain defect patterns of WBMs provide engineers with information to isolate manufacturing problems. However, some WBMs may be masked at a small or large area due to the sequential circuit probe tests for bin codes. We proposed a new modified Radon transformation to extract features for better clustering. We demonstrated our procedure on synthetic WBMs with various defect patterns and levels of masking through a simulation study.

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